

Optimisation of CO₂ laser-produced Sn plasmas for next generation semiconductor lithography sources

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1. Introduction

- Research to date [1] has identified CO₂ laser produced plasmas (LPPs) of Sn as a viable Extreme Ultra-violet Lithography (EUVL) source candidate
- CO₂ LPPs have demonstrated an increased in-band conversion efficiency (CE) when compared to the Nd:YAG, due in the main to reduced opacity effects [2]
- Pulse shortening techniques of the CO₂ temporal profile have been reported [3] along with CE values of 3-4% [4], however theoretical modelling has shown the potential to improve this figure

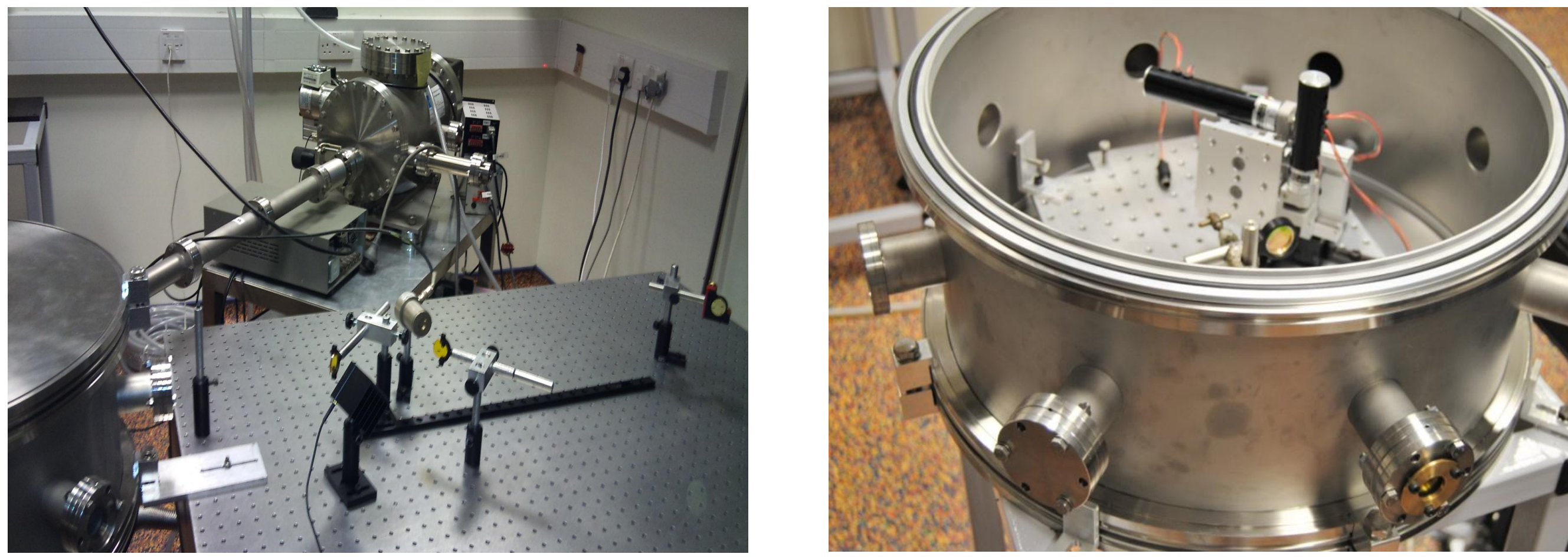


Figure 1(a) & (b): Images of lab layout and inside the chamber

3. Results

- By varying the lens position, the on target power density was also varied and the CE as a function of focus is shown
- Fig. 3 and 4 show variation between the CE values obtained at 45° and 90° to target normal were observed
- Through varying the gas mixture in the laser chamber, 5:2:3 of He:CO₂:N₂ was found to demonstrate the highest CE with a maximum at 2%

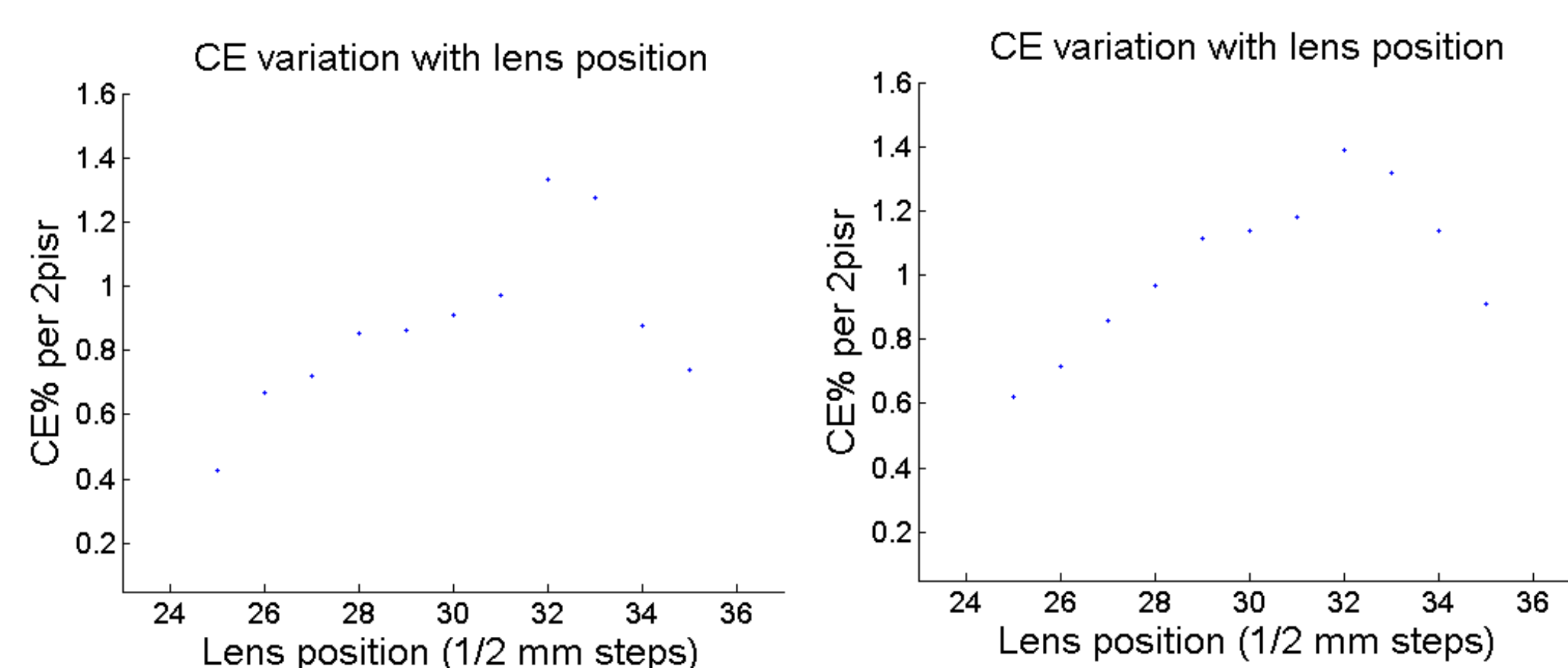


Figure 3(a) & (b): CE with different lens positions for 6:1:3 and 5:2:3 mixes at 45° to target normal

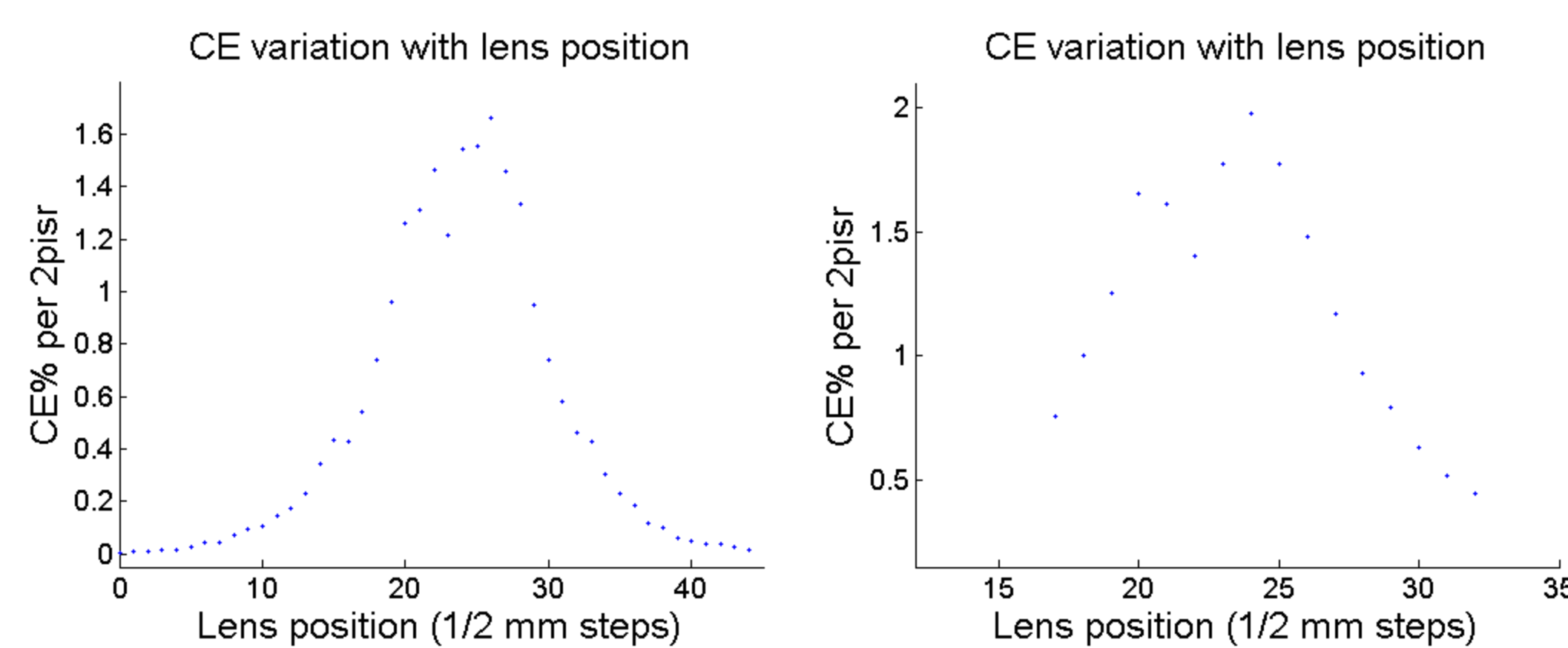


Figure 4(a) & (b): CE with different lens positions for 6:1:3 and 5:2:3 mixes at 90° to target normal

- CE results presented were less than reported and theoretical values
- A novel plasma shutter was designed and implemented which, when adjusted, clipped the N₂ tail from the typical CO₂ laser temporal profile and allowed control over the duration of the pulse, the results of which are shown in Fig. 5-10
- Pulse duration of 2-50ns achieved with energies from 20-700mJ
- Fig. 7 and 10 shows a reasonable agreement between the measured pulse lengths and calculations using a simple laser heating model [5]

2. Experimental set-up

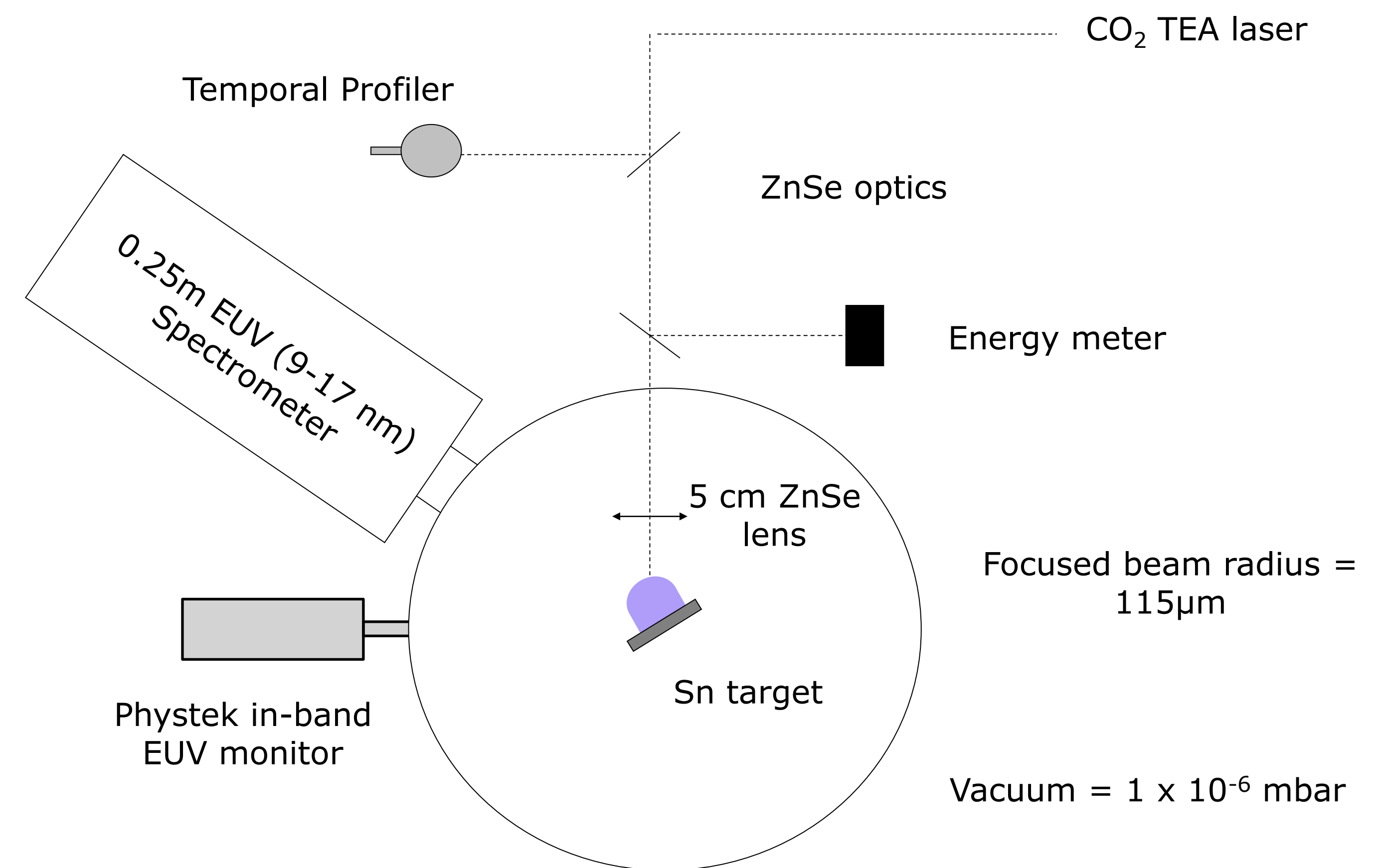


Figure 2: Laboratory set-up for obtaining EUV spectra at 90° to target normal and EUV monitor at 45°

- Fig. 1 and 2 shows the set-up used to acquire EUV spectra. A TEA CO₂ laser delivering up to 400mJ in 50ns, at a wavelength of 10.6µm was used to irradiate the target
- Temporal profile and pulse energy were measured for each shot due to variation in the laser from pulse to pulse. Spectra produced with the EUV spectrometer at 45° to target normal.

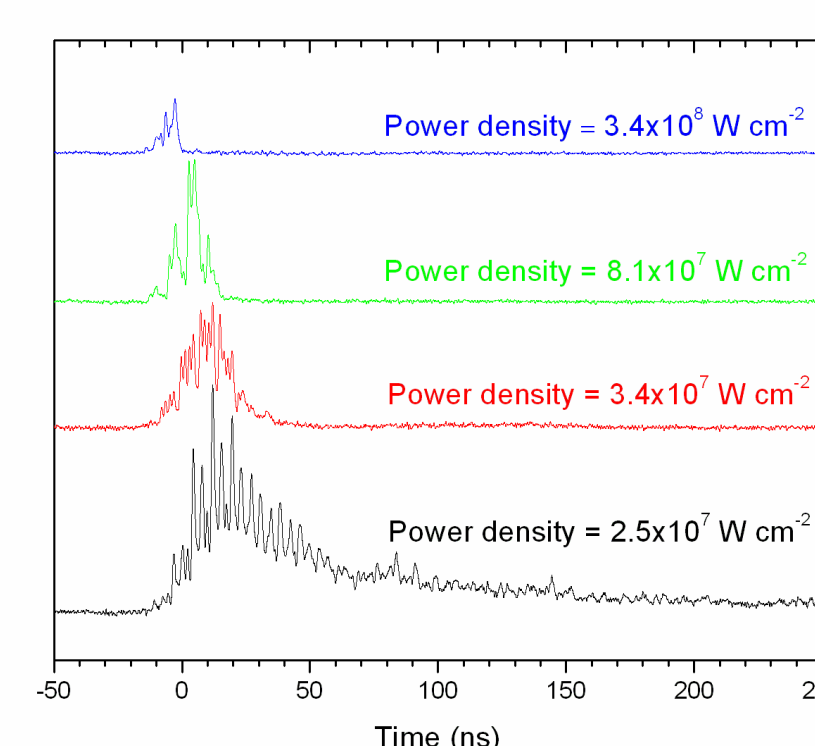


Figure 5: Shortened pulse profiles

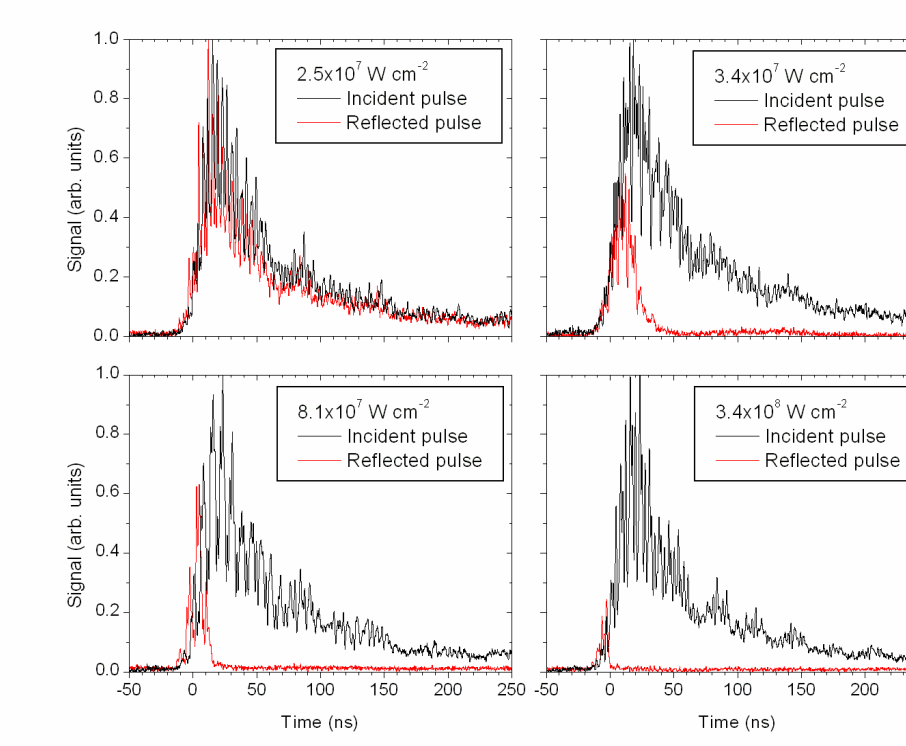


Figure 6: Shortened pulses with original profiles

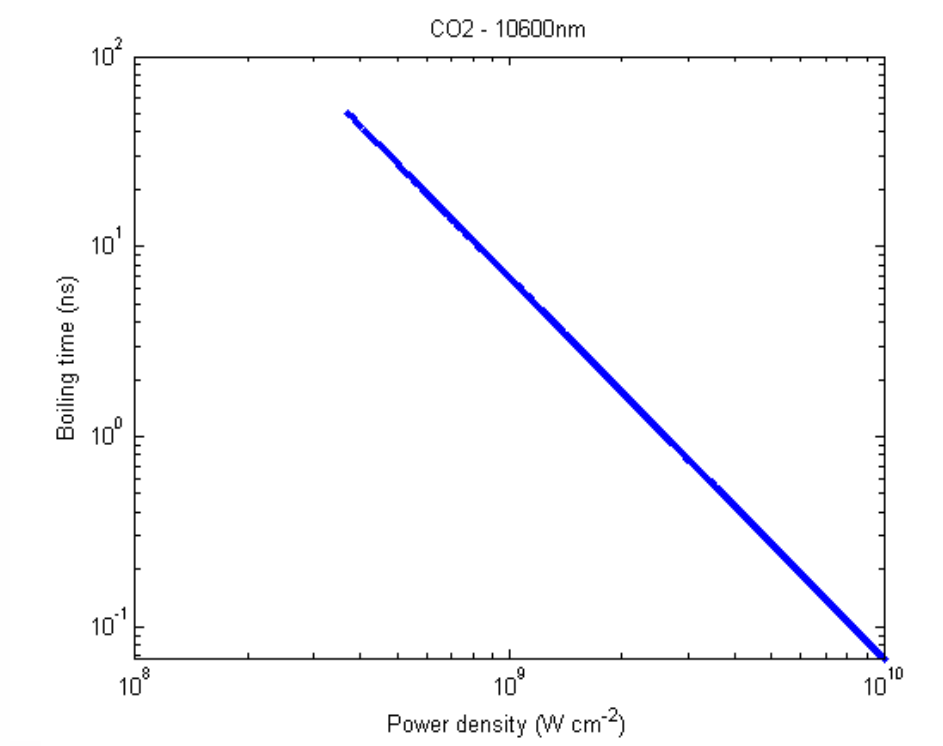


Figure 7: Calculated surface boiling times

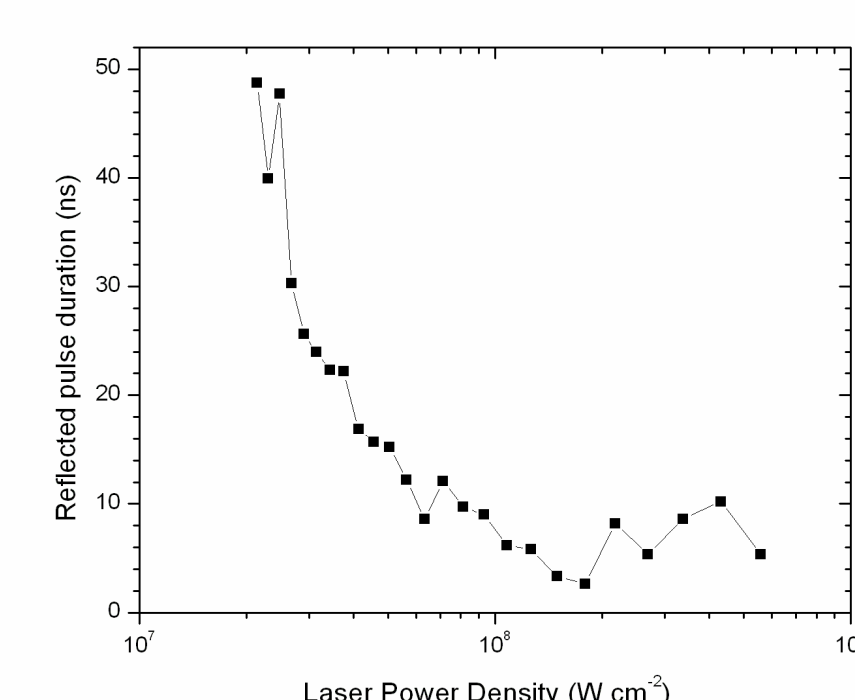


Figure 8: Shortened pulse durations

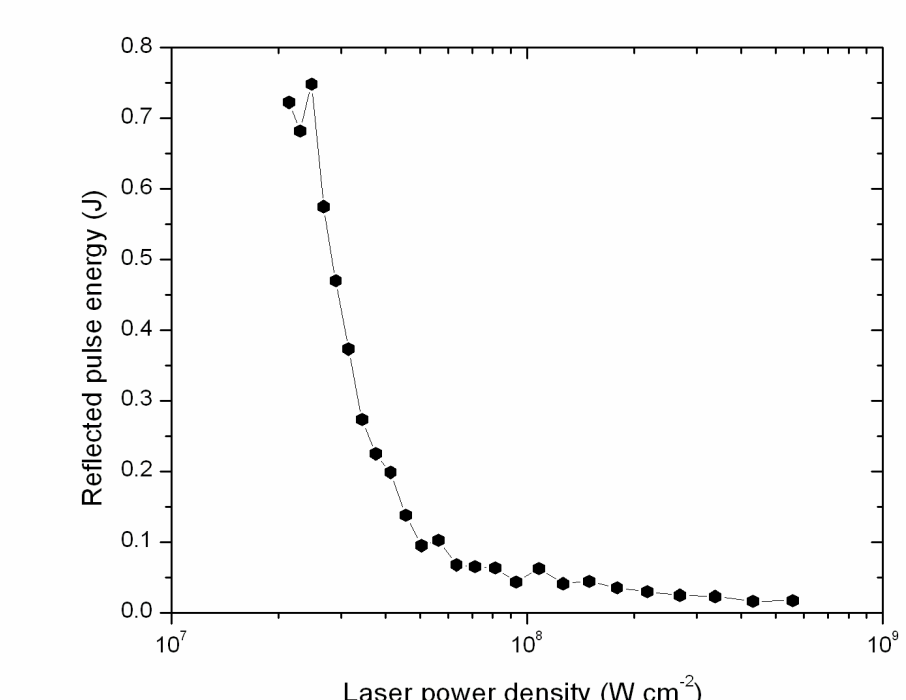


Figure 9: Shortened pulse energies

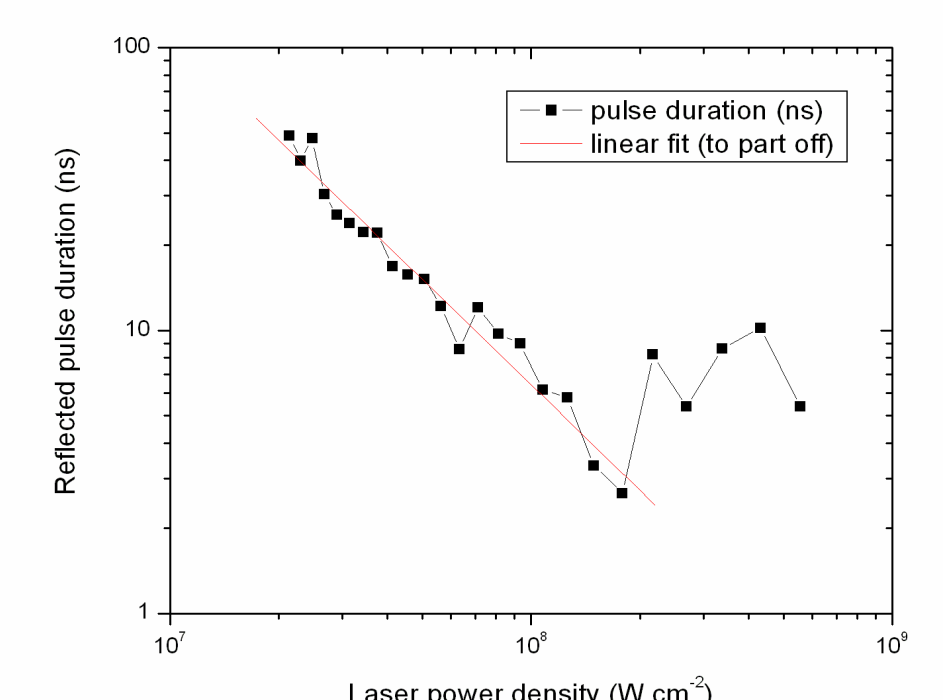


Figure 10: Pulse durations with linear fit

- Future work will consist of using these very short pulses to irradiate a range of targets including; solid Sn, mass limited Sn, novel target metals and plasma targets

4. References

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